

High Performance Computing (HPC)-Accelerated Inverse Deflectometry for Mirror Segment Metrology – *Update*

Presentation to
NASA Mirror Tech / SBIR / STTR Workshop 2016

Contributors

Prime Contractor (SBIR)
SURVICE Engineering

Dr. John F. Ebersole, Principal Investigator
Dr. Christiaan Gribble
Dr. Shawn Recker
Robert Baltrusch
Mark Butkiewicz
Dr. Joseph Rosenthal

Subcontractor

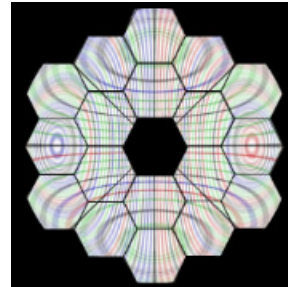
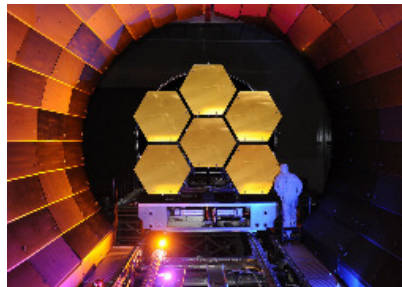
UNC Charlotte / Ctr for Precision Metrology

Dr. Angela Davies, Principal Investigator
Trent Vann
Dr. Chris Evans
Dr. Joseph Owen

NASA GSFC Tech Rep: [Dr. Raymond G. Ohi](#)
2 NOV 2016

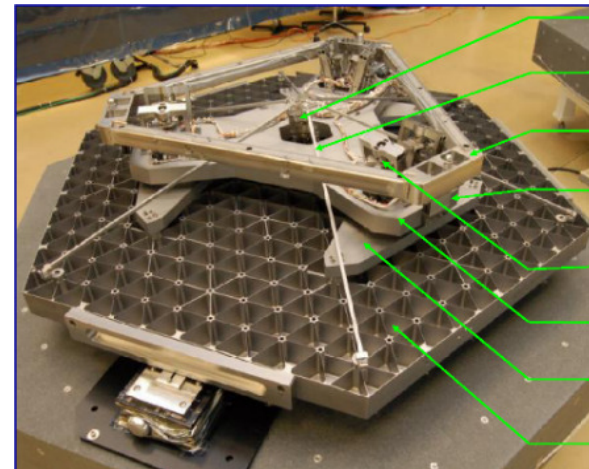
M-TEC™ : *Inverse* Deflectometry + HPC

- Instead of using *deflectometry* to determine the optical prescription (shape) of a telescope mirror
- We have been developing *inverse* deflectometry
- We start by assuming we already know the actual optical prescription of the telescope mirror
 - Then use deflectometry to determine 6 DOF misalignment of mirror segments in the telescope
 - And accelerate the process with *high performance computing* (HPC) to rapidly determine misaligned 6 DOF condition
- Our name for this new metrology technology is *M-TEC™*

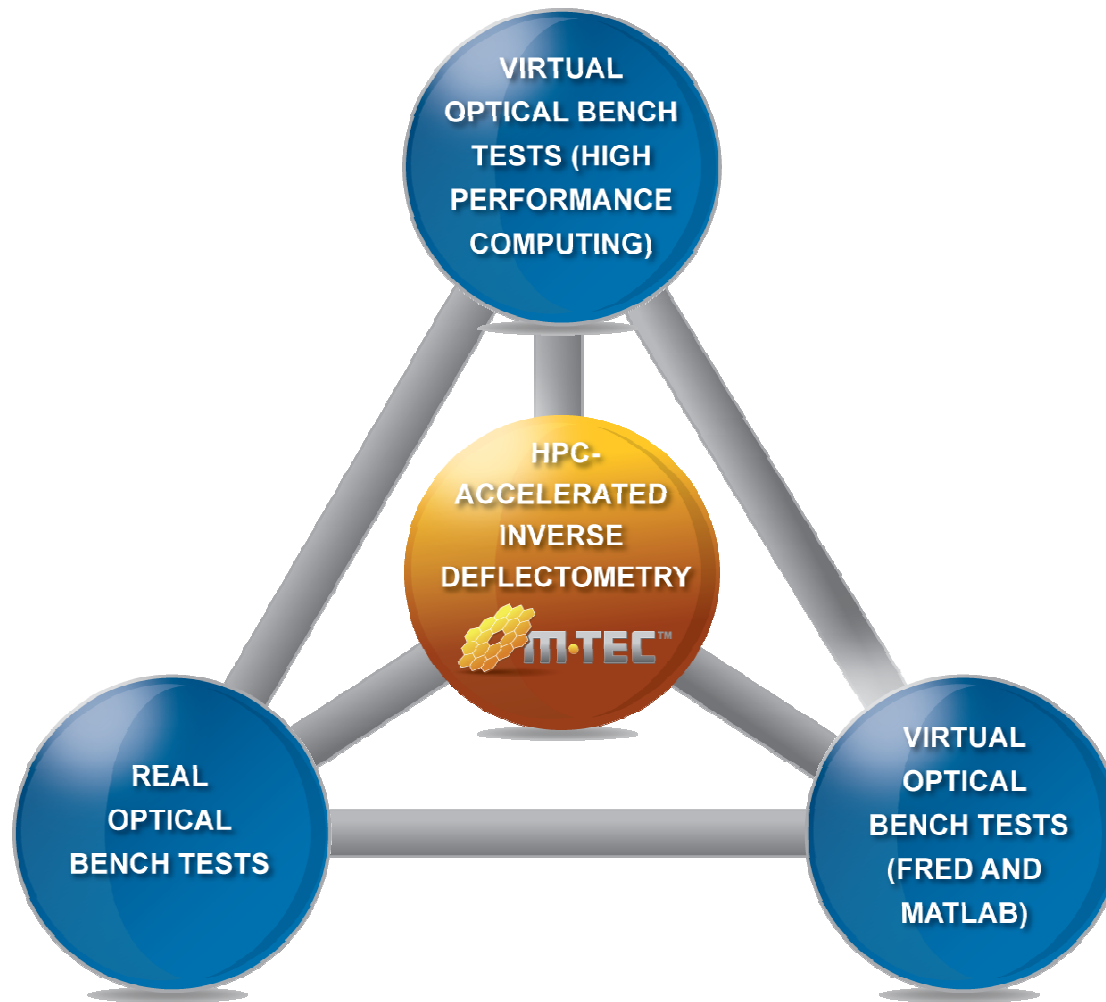


M-TEC™ Permits Direct (Front-Viewing) Determination of Segment Alignment

- Allows front-viewing, *in situ* testing of segment alignment
 - Non-contact
 - At safe distance (greater than one meter)
 - Multi-segmented telescopes and optics
- Versus metrology tech mounted onto reverse

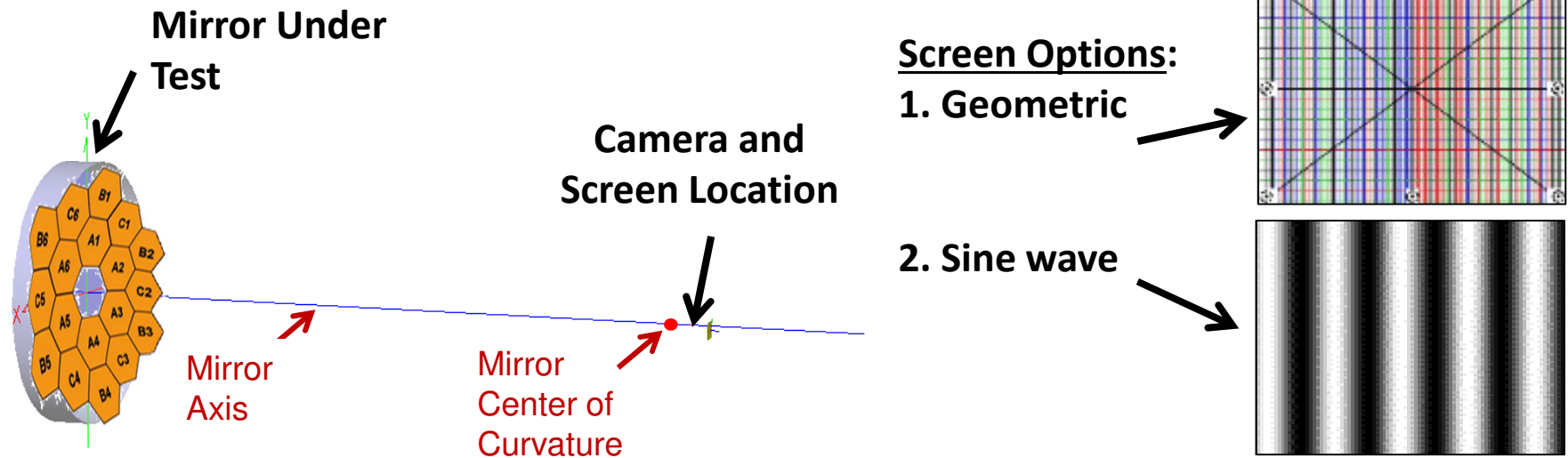


M-TEC™ Development & Validation Process



Inverse Deflectometry = New Twist on Prior Art

(Phase Measuring Inverse Deflectometry, or PMID)

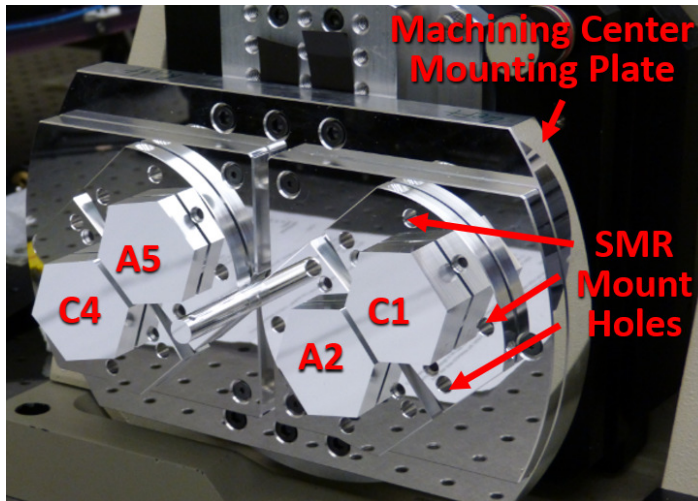


Leverages prior work in deflectometry; for example

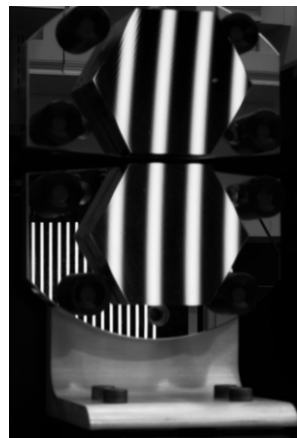
- PMD (Phase Measuring Deflectometry) work by Knauer *et al.*, SPIE Proc. 5457, 366 -376 (2004)
- SCOTS (Software Configurable Optical Test System) work by Su *et al.*, Appl. Opt. 49, 4404 – 4412 (2010)

Optical Bench Tests

Diamond-turned off-axis
parabolic mirrors

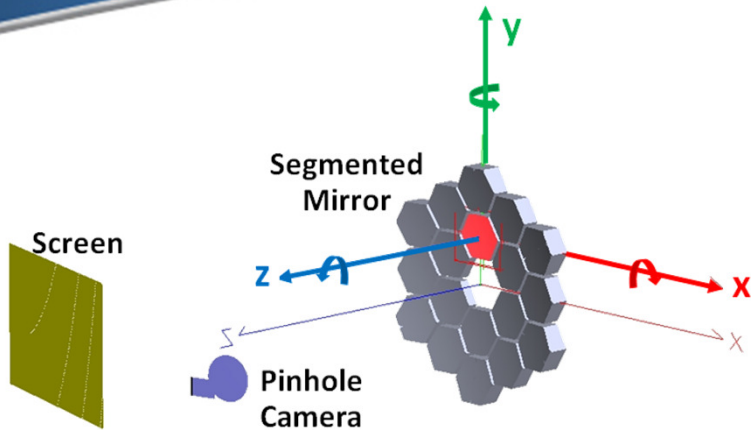


Optical Layout

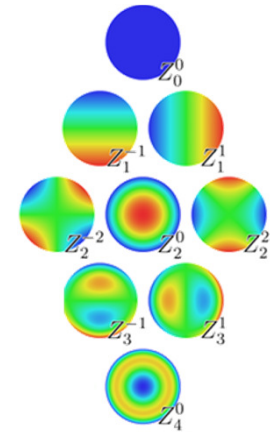


Sinusoidal Fringes
on Screen Seen
Via Mirrors

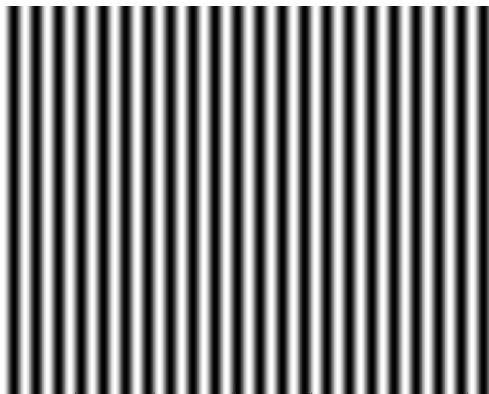
Zernike Analytic Methodology



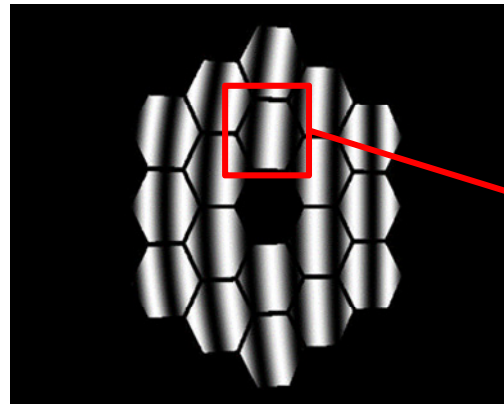
- Goal: 6 DOF misalignment
Range: ± 2 mm & ± 2 mrad
Sensitivity: $100 \mu\text{m}$ & $100 \mu\text{rad}$
(JWST 1.6 m segment scale)
- Low-order Zernike fit
- Track Zernike coefficients with misalignment
- Simulate with FRED



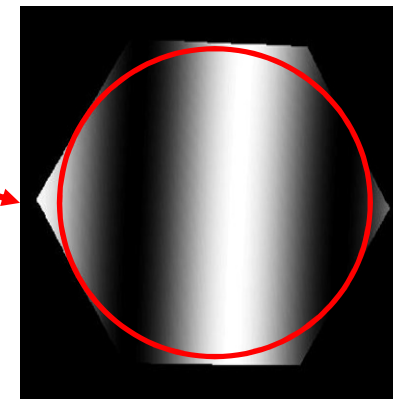
Screen Pattern



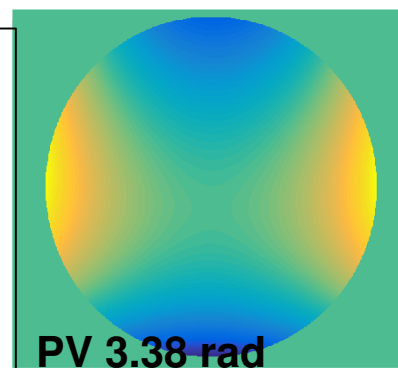
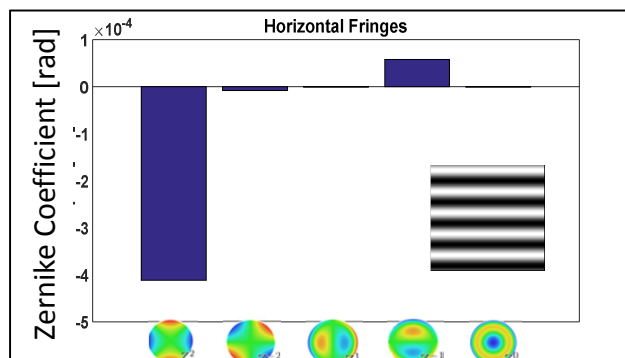
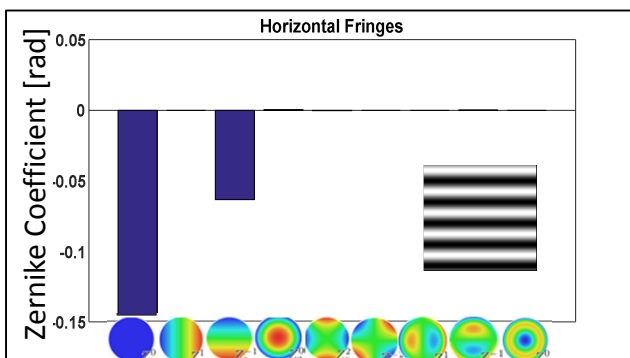
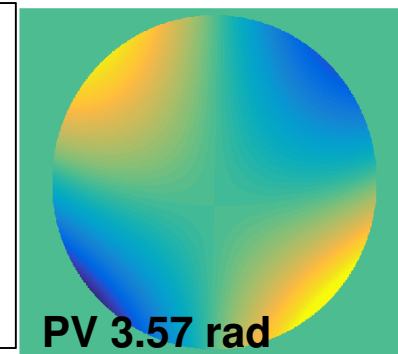
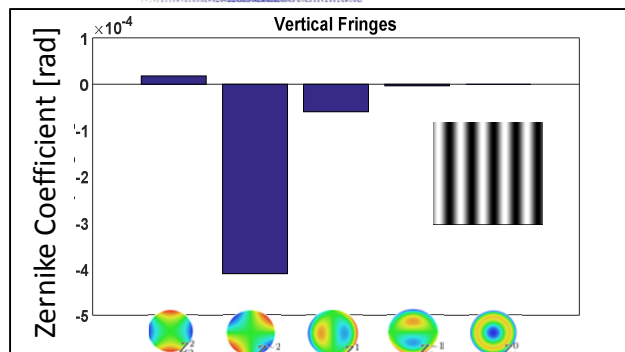
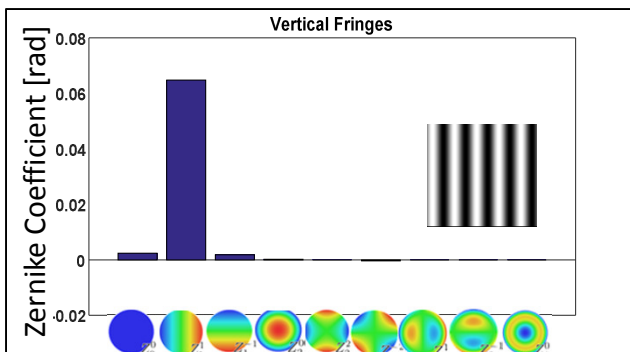
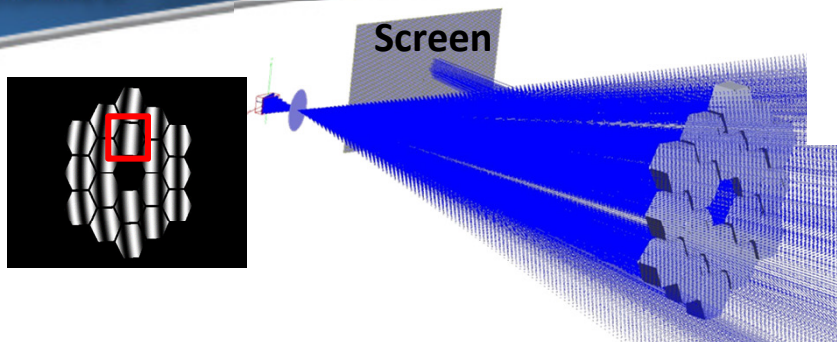
Simulated Camera Image



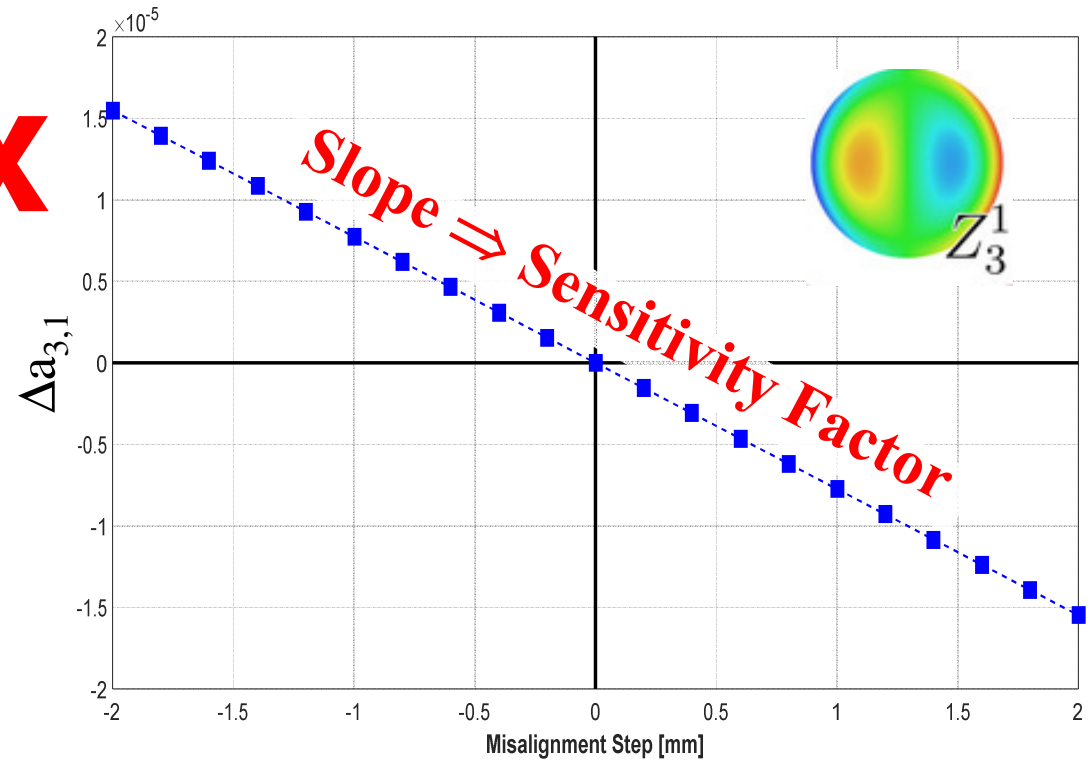
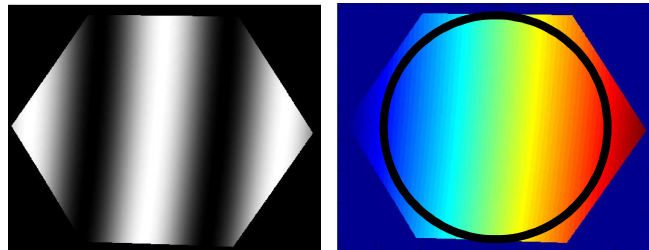
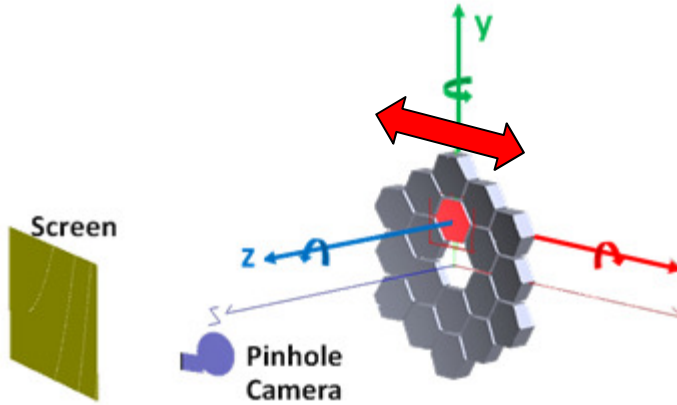
Individual Segment



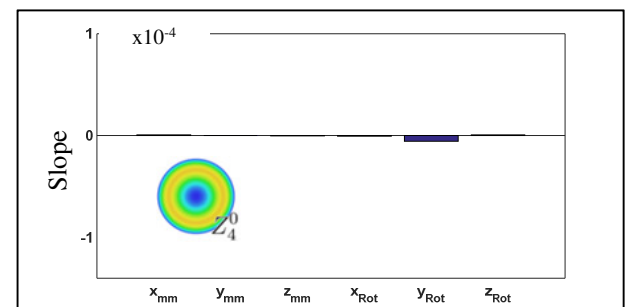
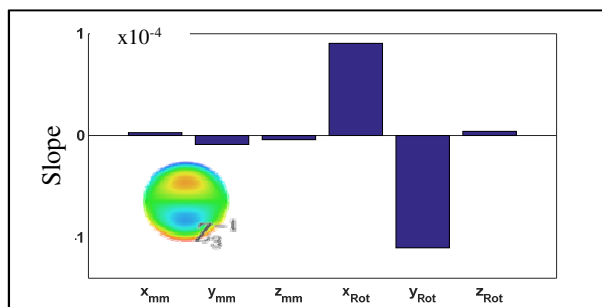
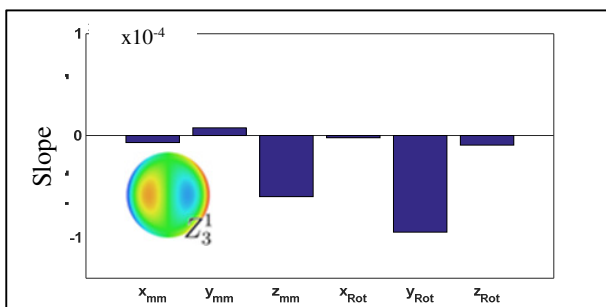
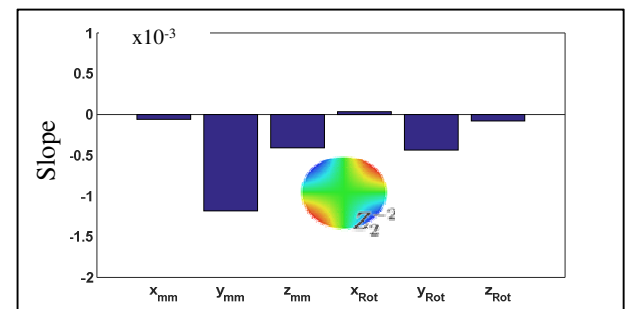
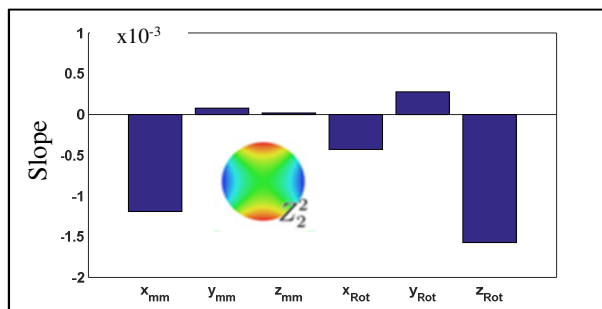
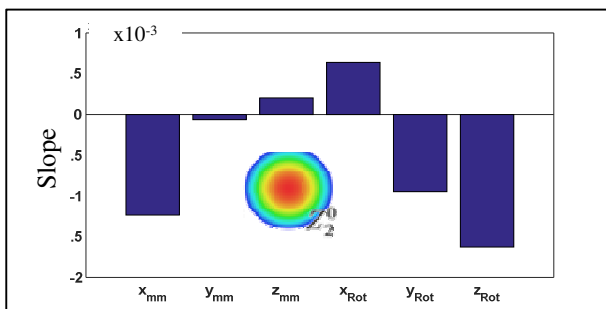
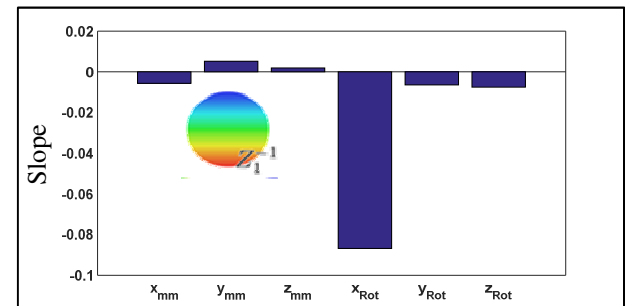
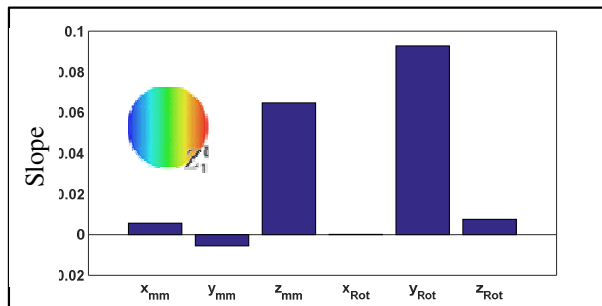
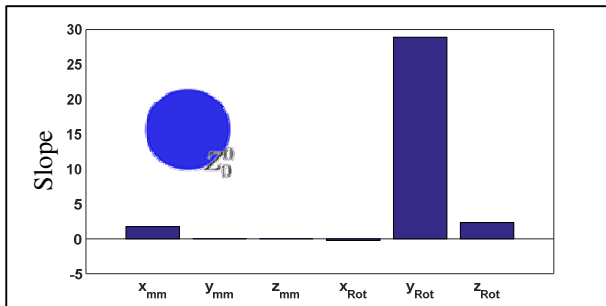
Zernike Signature of JWST-scale Aligned



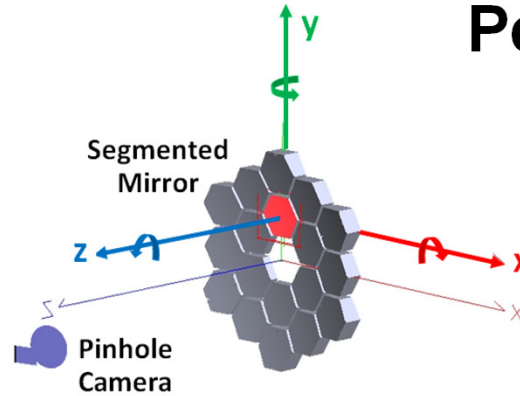
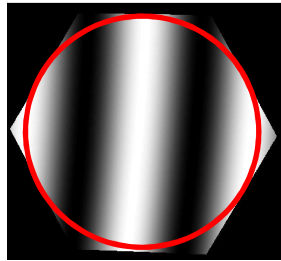
Linear Behavior Observed e.g., X Translation Misalignment



Sensitivity Factors Vertical Fringes



Perform Nonlinear Fit to Mathematical Model



Taylor series expansion of Zernikes vs misalignment:

Experiment or Simulation

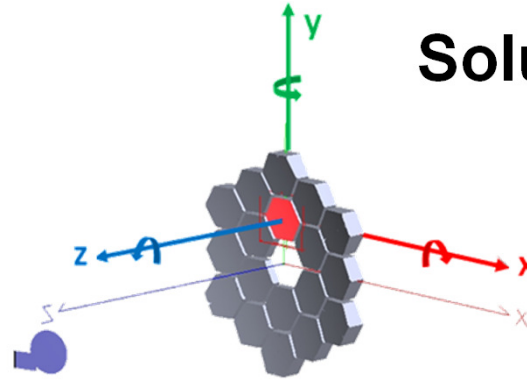
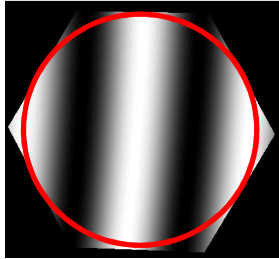
$$\Delta a_n^m = f(\Delta x, \Delta y, \Delta z, \Delta x_{rot}, \Delta y_{rot}, \Delta z_{rot})$$

$$\Delta a_n^m = \frac{\partial a_n^m}{\partial x} \Delta x + \frac{\partial a_n^m}{\partial y} \Delta y + \frac{\partial a_n^m}{\partial z} \Delta z + \frac{\partial a_n^m}{\partial x_{rot}} \Delta x_{rot} + \frac{\partial a_n^m}{\partial y_{rot}} \Delta y_{rot} + \frac{\partial a_n^m}{\partial z_{rot}} \Delta z_{rot} +$$

Quadratic Terms \rightarrow $\frac{1}{2} \frac{\partial^2 a_n^m}{\partial x^2} \Delta x^2 + \frac{1}{2} \frac{\partial^2 a_n^m}{\partial y^2} \Delta y^2 + \dots + \frac{1}{2} \frac{\partial^2 a_n^m}{\partial y_{rot}^2} \Delta y_{rot}^2 + \frac{1}{2} \frac{\partial^2 a_n^m}{\partial z_{rot}^2} \Delta z_{rot}^2 +$

Cross Terms \rightarrow $\frac{\partial^2 a_n^m}{\partial x \partial y} \Delta x \Delta y + \frac{\partial^2 a_n^m}{\partial x \partial z} \Delta x \Delta z + \dots + \frac{\partial^2 a_n^m}{\partial x \partial z_{rot}} \Delta x \Delta z_{rot} + \dots$

Solution via Nonlinear Fit

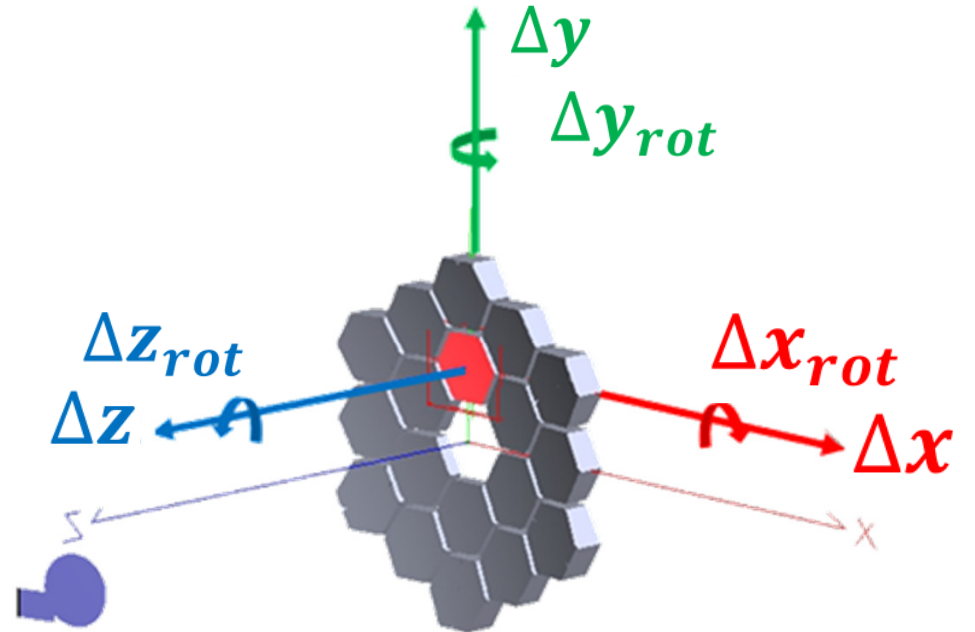


$$\Delta a_n^m = f(\Delta x, \Delta y, \Delta z, \Delta x_{rot}, \Delta y_{rot}, \Delta z_{rot})$$

$$\Delta a_n^m = \frac{\partial a_n^m}{\partial x} \Delta x + \frac{\partial a_n^m}{\partial y} \Delta y + \frac{\partial a_n^m}{\partial z} \Delta z + \frac{\partial a_n^m}{\partial x_{rot}} \Delta x_{rot} + \frac{\partial a_n^m}{\partial y_{rot}} \Delta y_{rot} + \frac{\partial a_n^m}{\partial z_{rot}} \Delta z_{rot} +$$

$$\frac{1}{2} \frac{\partial^2 a_n^m}{\partial x^2} \Delta x^2 + \frac{1}{2} \frac{\partial^2 a_n^m}{\partial y^2} \Delta y^2 + \dots + \frac{1}{2} \frac{\partial^2 a_n^m}{\partial y_{rot}^2} \Delta y_{rot}^2 + \frac{1}{2} \frac{\partial^2 a_n^m}{\partial z_{rot}^2} \Delta z_{rot}^2 +$$

$$\frac{\partial^2 a_n^m}{\partial x \partial y} \Delta x \Delta y + \frac{\partial^2 a_n^m}{\partial x \partial z} \Delta x \Delta z + \dots + \frac{\partial^2 a_n^m}{\partial x \partial z_{rot}} \Delta x \Delta z_{rot} + \dots$$



SURVICE Engineering Company

www.survice.com

Nationwide 350+ employee specialty engineering consulting and design firm, serving the US Department of Defense for over 30 years.

- Recognized expert in visualization and high performance computing
 - Only small business with NVIDIA CUDA Research Center accreditation
- Recognized leader in metrology and reverse engineering services (metrology.survice.com)
- Dozens of highly competitive Small Business Innovation Research (SBIR) awards



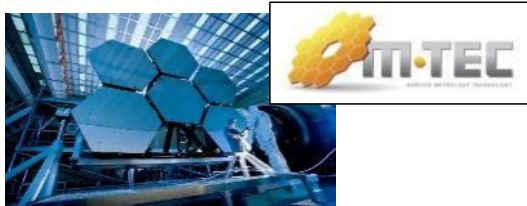
SURVICE leverages massively parallel computing architectures from NVIDIA and Intel



SmartCEO Magazine
Voltage Award for
Technology Innovation



SURVICE Engineering CR&D HPC and Metrology Devices & Tech



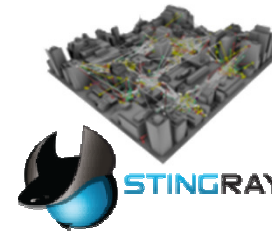
M-TEC™

NASA SBIR to develop HPC metrology tech, like James Webb Space Telescope



Hoverbike

DSIAC task with US Army & Malloy Aeronautics Ltd.



New RF propagation model built for Intel to showcase Xeon Phi



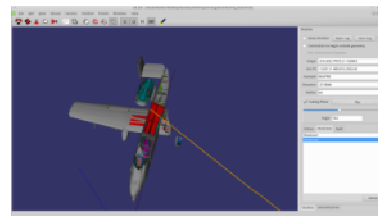
Enhanced-CLR™

Completed MRL-7 demo on F-35 production line in Palmdale CA.



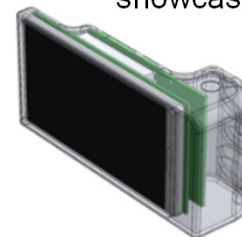
HOLOS™

Working with Intelligent Earth Ltd. on low-cost touch-probe metrology tech



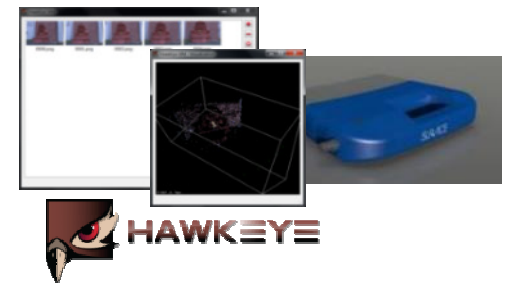
VSL (Visual Sim Lab)

High performance V/L analyses to be part of next AJEM release.

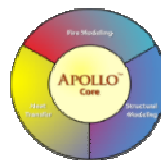


P&W (Pratt & Whitney) FAST II

Custom H/W & S/W solution for F-22 engine exhaust duct data collection



SURVICE-developed 3D scanning hardware & software

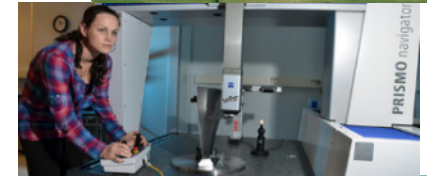


Apollo™

CFD running NVIDIA's CUDA on GPU

Subcontractor: **UNC Charlotte Center for Precision Metrology (CPM)**

- Research: Development and integration of precision metrology as applied to manufacturing
- Facilities:
 - 4,000 sq. ft. of controlled environment for metrology and instrument development
 - 1,500 sq. ft. controlled environment, $20 \pm 0.1^{\circ}$ C, class 10,000 metrology laboratory
 - 33,000 sq. ft. laboratories & offices Duke Centennial Hall
- Extensive capabilities
 - Metrology
 - Precision manufacturing
- CPM Affiliates: B&W Y-12, Zeiss, Caterpillar, Corning Cable, Cummins, GE Energy, General Dynamics, Intel, LLNL, Micro Encoder, NIST, Renishaw, United Technologies



~ Recap ~

High Performance Computing (HPC)-Accelerated Inverse Deflectometry for Mirror Segment Metrology – *Update*

